See all 6 Products in Family

# Olympus 20X WLI Objective

See More by Olympus

Stock #91-173 NEW 1 In Stock

- 1 + £5,261.50

ADD TO CART

| Volume Pricing | |
|---|---|
| Qty 1+ | **£5,261.50** each |
| Need More? | Request Quote |

Prices shown are exclusive of VAT/local taxes

Product Downloads

## General

**Model Number:**
WLI20XMRTC

**Compatible Tube Lens Focal Length (mm):**
Focal Length: 180mm

**Type:**
Microscope Objective

**Style:**
Infinity Corrected

**Manufacturer:**

Olympus

**Note:**
Designed to be used with a 180mm Tube Lens,
Sold Separately

## Physical & Mechanical Properties

**Field of View (mm):**
1.1

**Length excluding Threads (mm):**
44.00

**Maximum Diameter (mm):**
29.8

## Optical Properties

**Focal Length FL (mm):**
9.00

**Magnification:**
20X

**Numerical Aperture NA:**
0.60

**Resolving Power (µm):**
0.56

**Depth of Field (µm):**
0.76

**Working Distance (mm):**
1

**Field Number (mm):**
22

**Parfocal Length (mm):**
45

**Depth of Focus (µm):**
305.6

**Entrance Pupil Diameter (mm):**
10.80

## Threading & Mounting

**Mounting Threads:**
RMS / 20.32mm x 36 TPI

## Regulatory Compliance

**RoHS 2015:**
Exempt

**Certificate of Conformance:**
View

# Product Details

- Combines High Numerical Aperture and Broad Field of View
- Thermal Compensation & Stability Features
- Suitable for 3D Surface Metrology and Profilometry

Olympus WLI Infinity Corrected Interferometry Objectives' advanced optical design combines a high numerical aperture with a broad field of view, capturing fine surface details across large areas for visual clarity. Each objective features a built-in adjustment ring that compensates for temperature-induced focused shifts, allowing stability and consistent measurement accuracy even under unstable environmental conditions. These objectives are designed to be used with a 180mm focal length tube lens and are available in magnification of 10 – 50X. Olympus WLI Infinity Corrected Interferometry Objectives are ideal for 3D surface metrology and profilometry applications, including semiconductor inspection, precision machining, optical coating evaluation, and microelectronic characterization.

;